



SW Test Workshop
Semiconductor Wafer Test Workshop

A Proposal of Multi Para CIS Probe Card Concept for Improvement of PI/SI



Hyun Min Kim
Jung Keun Park

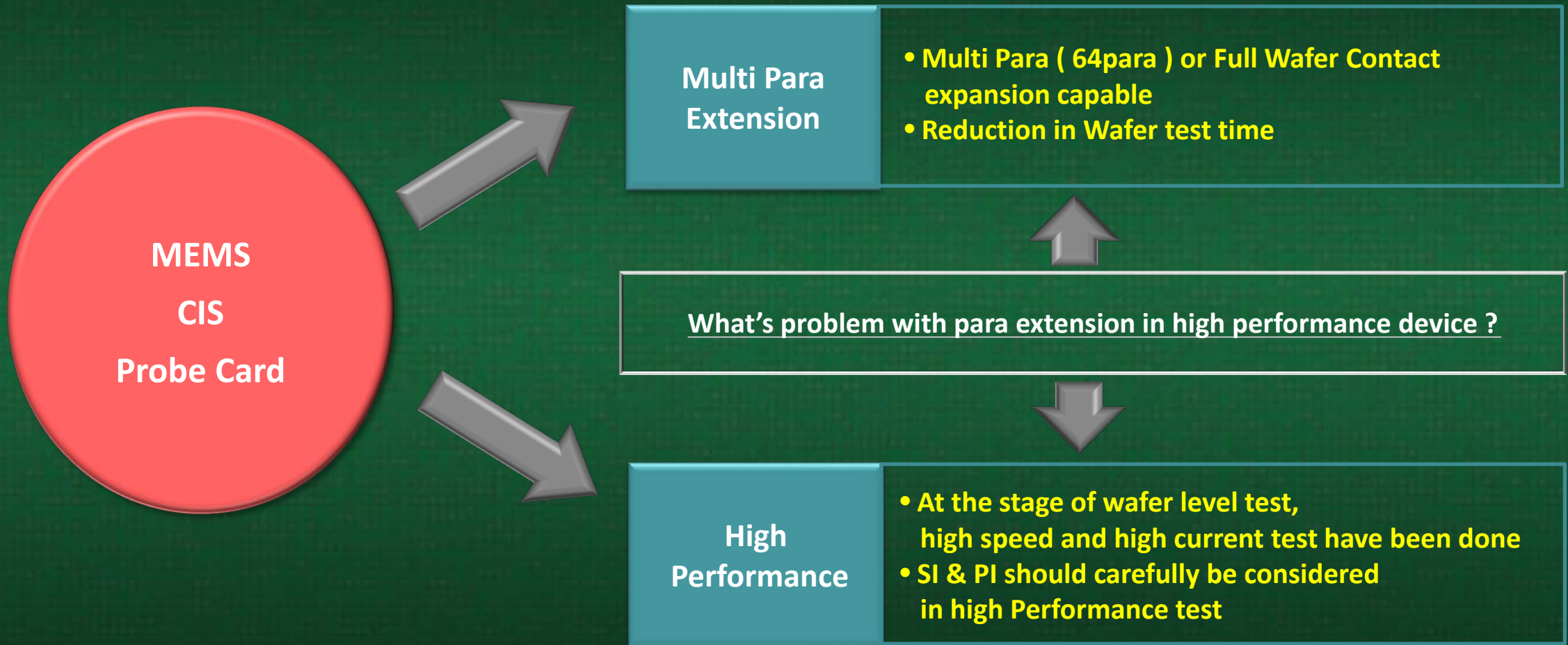
Willtechnology Co., Ltd.

June 4-7, 2017

Overview

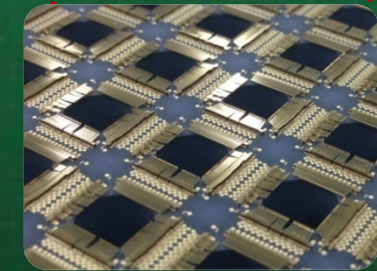
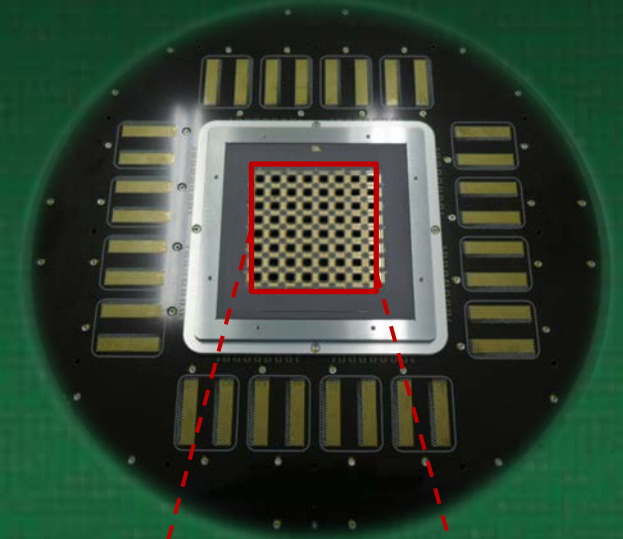
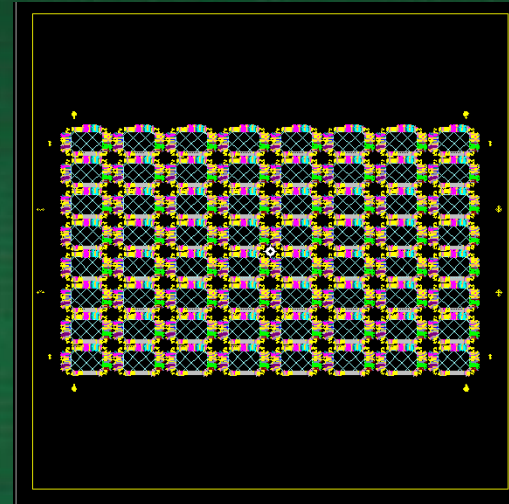
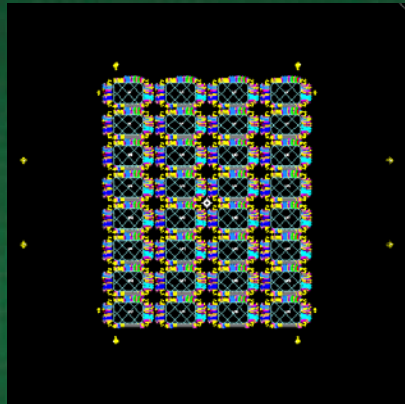
- **Introduction**
- **Problem due to Para Extension**
- **Design Concept**
- **Improve Power Integrity**
 - DC Resistance
 - AC Power Impedance
- **Improve Signal Integrity**
 - Insertion Loss
 - Eye Diagram
- **Conclusion & Future work**

Introduction



Problem due to Para Extension

- CIS Probe Card Para Extension



Benefit

- Reduction in Wafer test time

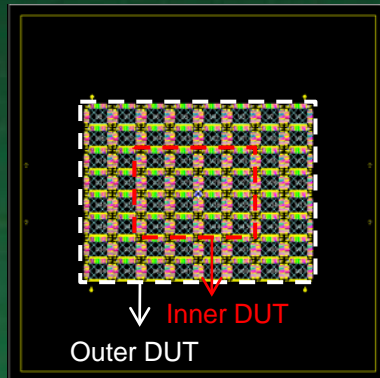
Problem

- Deviation between DUTs
- PI / SI degradation

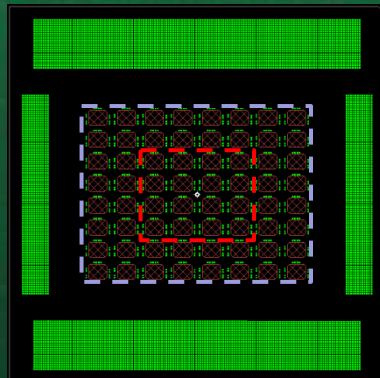
< 64Para MEMS CIS Probe Card >

Problem due to Para Extension

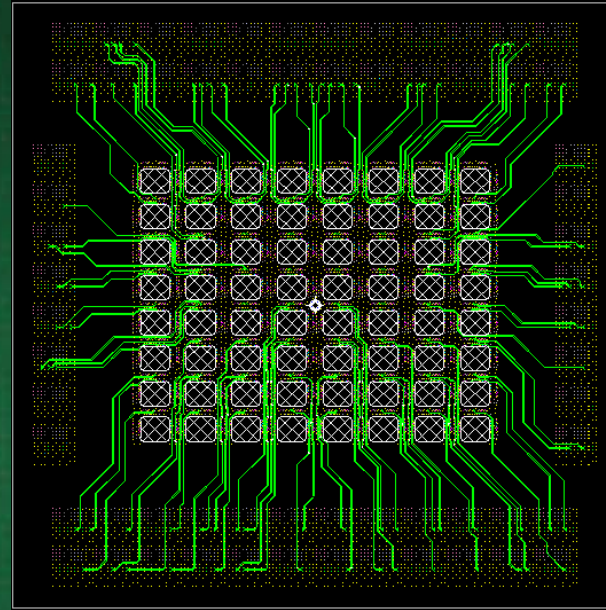
- MLC Design



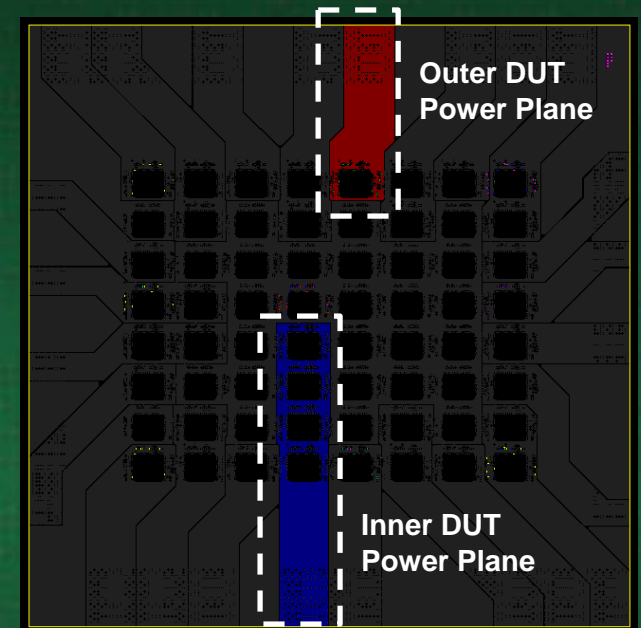
[MLC Top]



[MLC Bottom]



[Signal Layer]



[Power Layer]

Weak Point

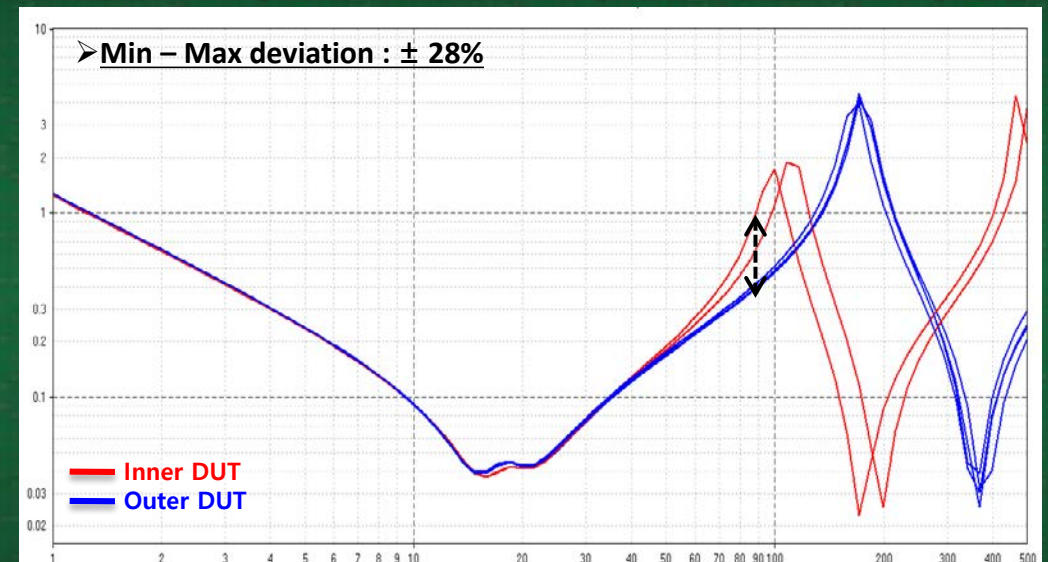
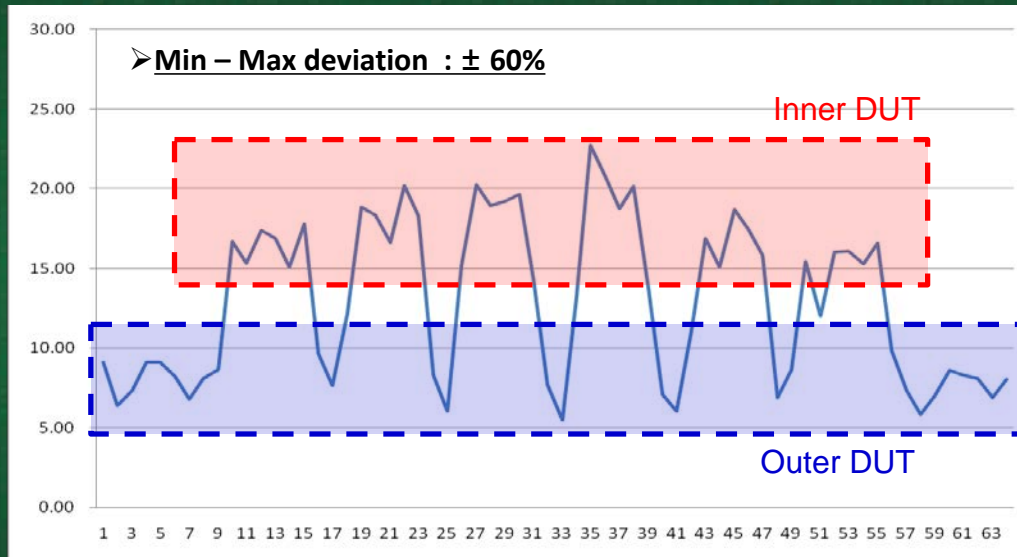
- As para extension, there is a physical distance difference between inner and outer DUT
- It cause SI & PI deviation between DUTs
- Higher Performance devices can cause more serious problems

Problem due to Para Extension

- **PI Deviation between DUTs**

[Power DC Resistance]

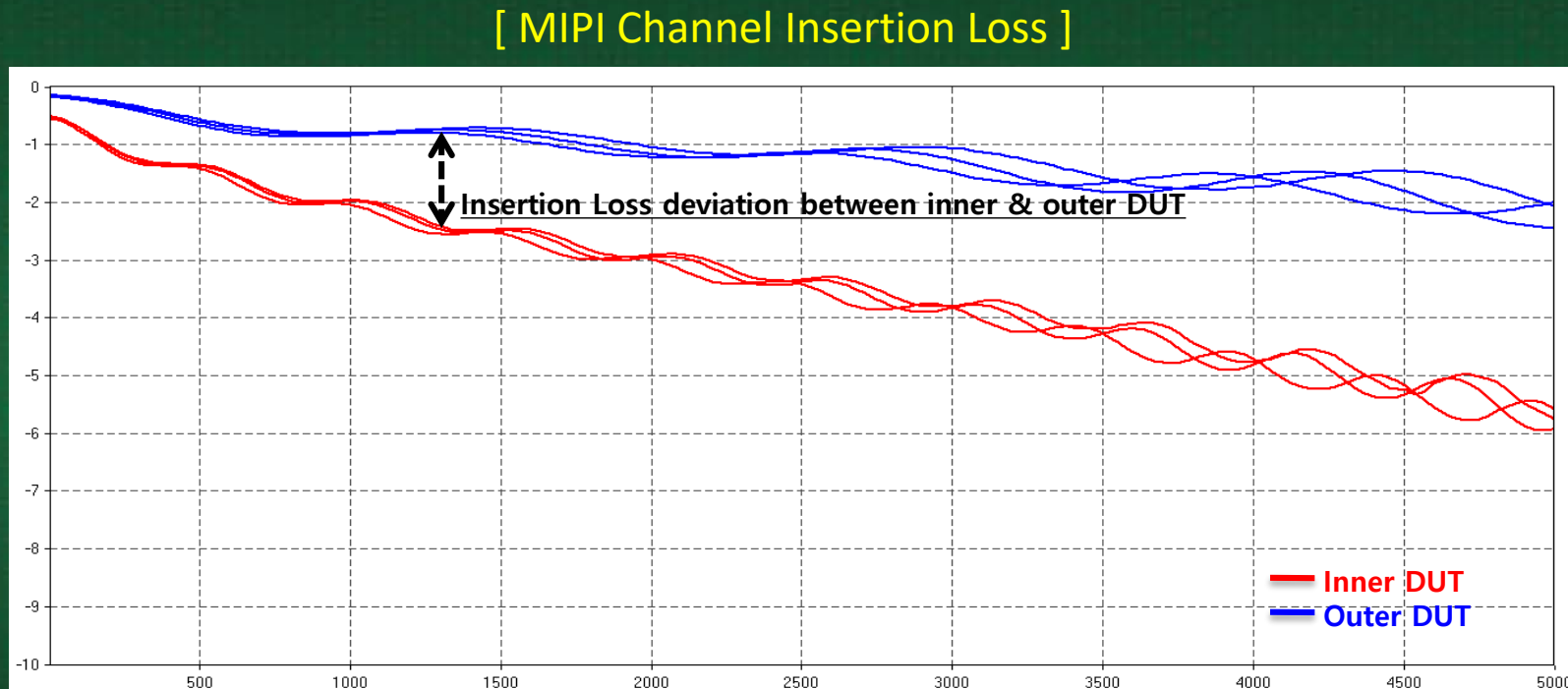
[PDN Impedance]



- Power DC Resistance Min - Max Deviation between DUTs is about $\pm 60\%$
- PDN impedance Min - Max Deviation between DUTs is about $\pm 28\%$
- These are two simulation results that shows deviation of PI by para extension

Problem due to Para Extension

- SI Deviation between DUTs



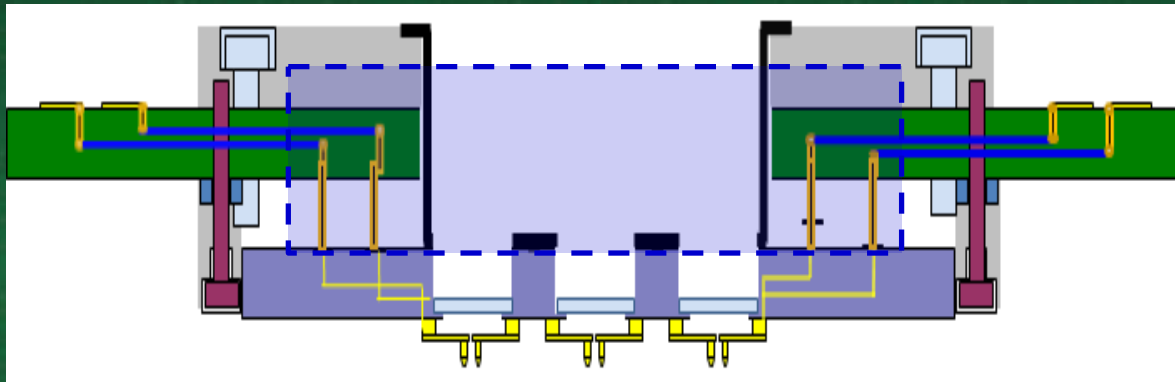
- Inner DUT has relatively high insertion loss level compared to the outer DUT

How to improve Deviation between Inner & Outer DUT ?

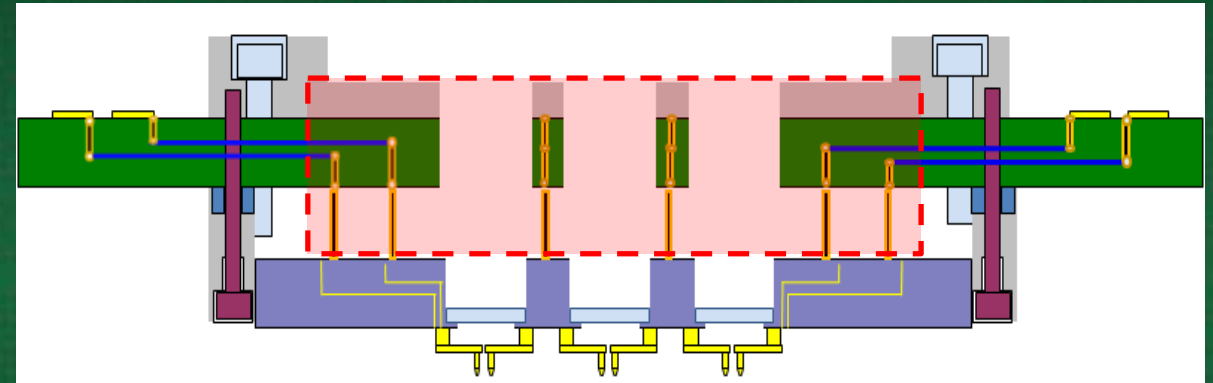
Design Concept

- Probe Card Structure

[Origin Concept]



[New Concept]

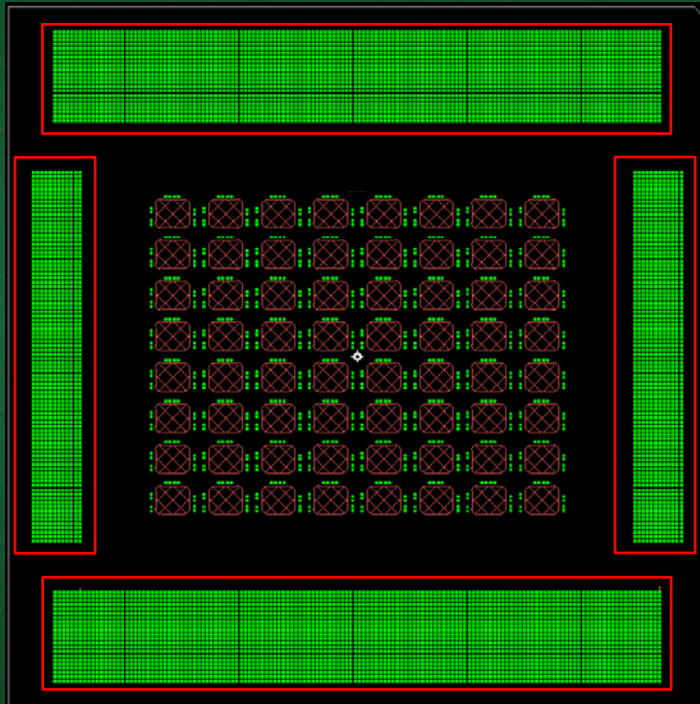


	Origin Concept	New Concept
STF		MLC
LGA Location on STF	Outside DUT Area	Inside DUT Area & Outside DUT Area

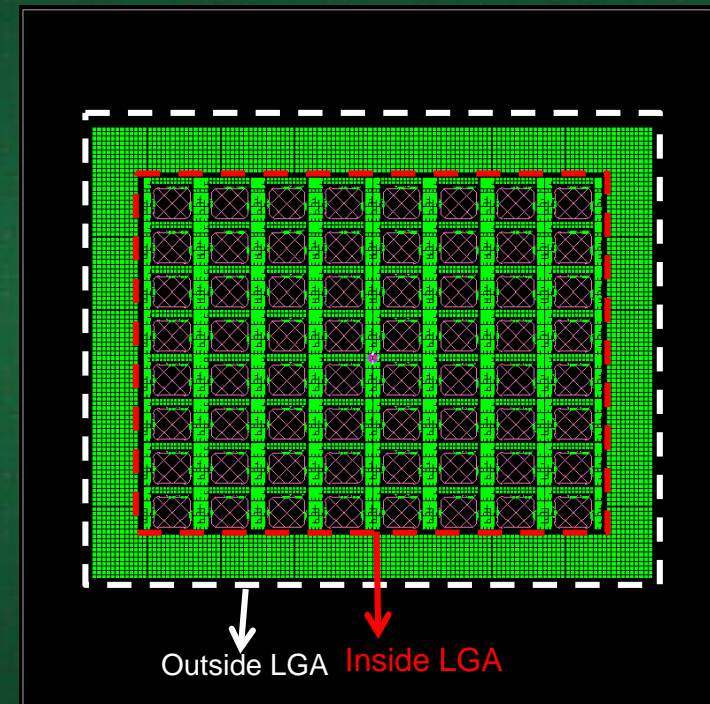
Design Concept

- MLC Design

[Origin Concept]



[New Concept]

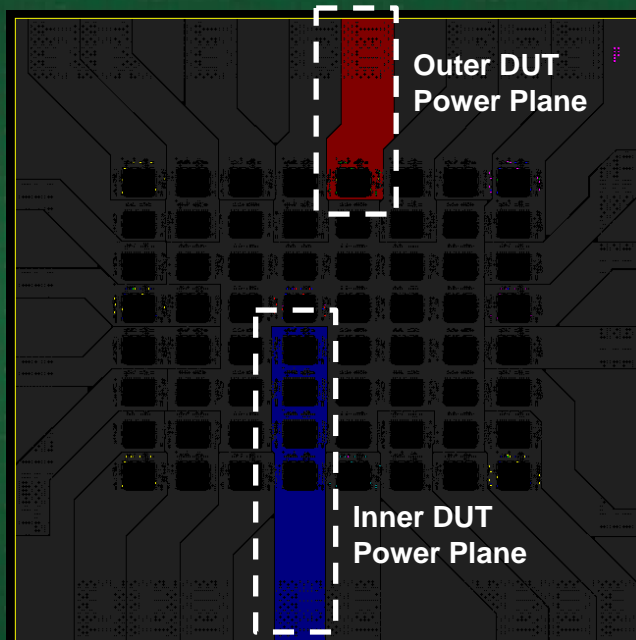


- Add LGA to DUT area
- Inside LGA Area - High Speed (ex. MIPI) & High Current Power placed

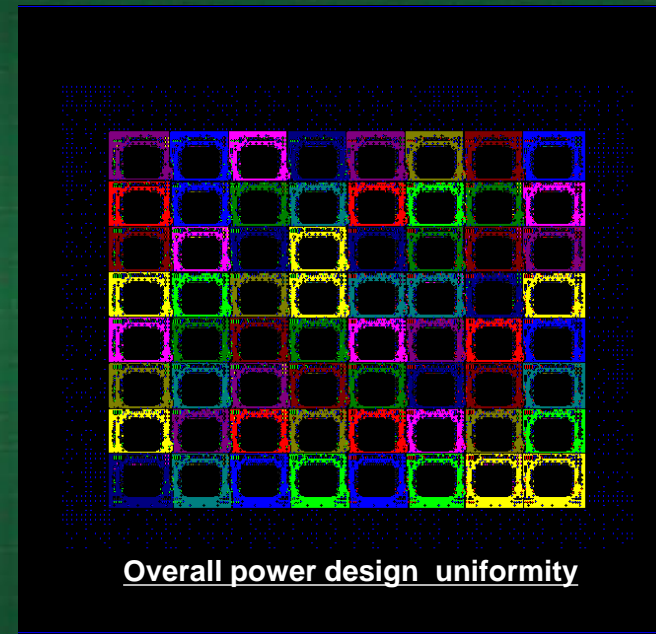
Design Concept

- **MLC Power Design**

[Origin Concept]



[New Concept]



**MLC
Power
Design**

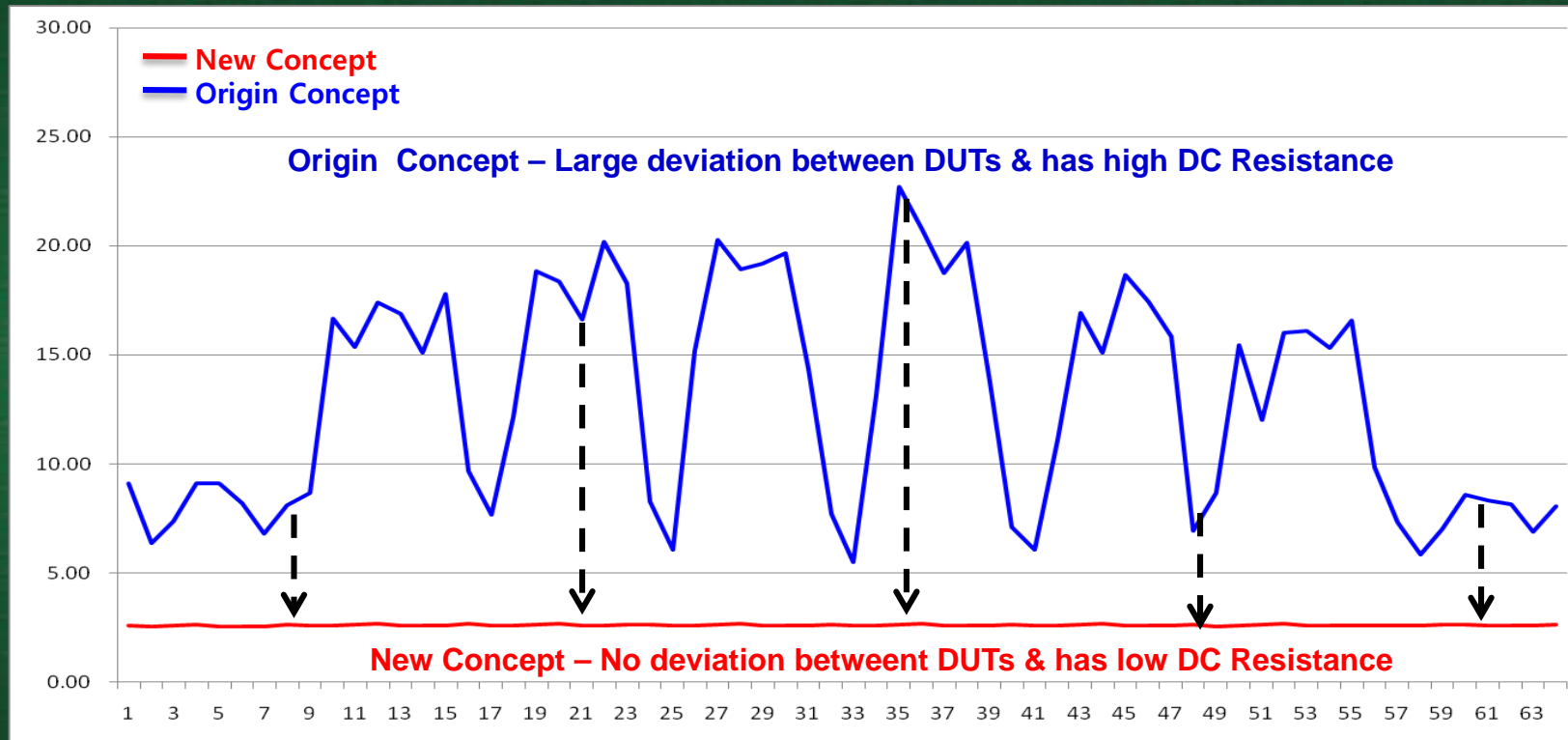
- Long Path length between DUT - LGA
- Different design for each DUT
- Required No. of Layer : Over 4 Layer



- Short Path length between DUT - LGA
- Same design for all DUT
- Required No. of Layer : Under 2 Layer

Improve Power Integrity

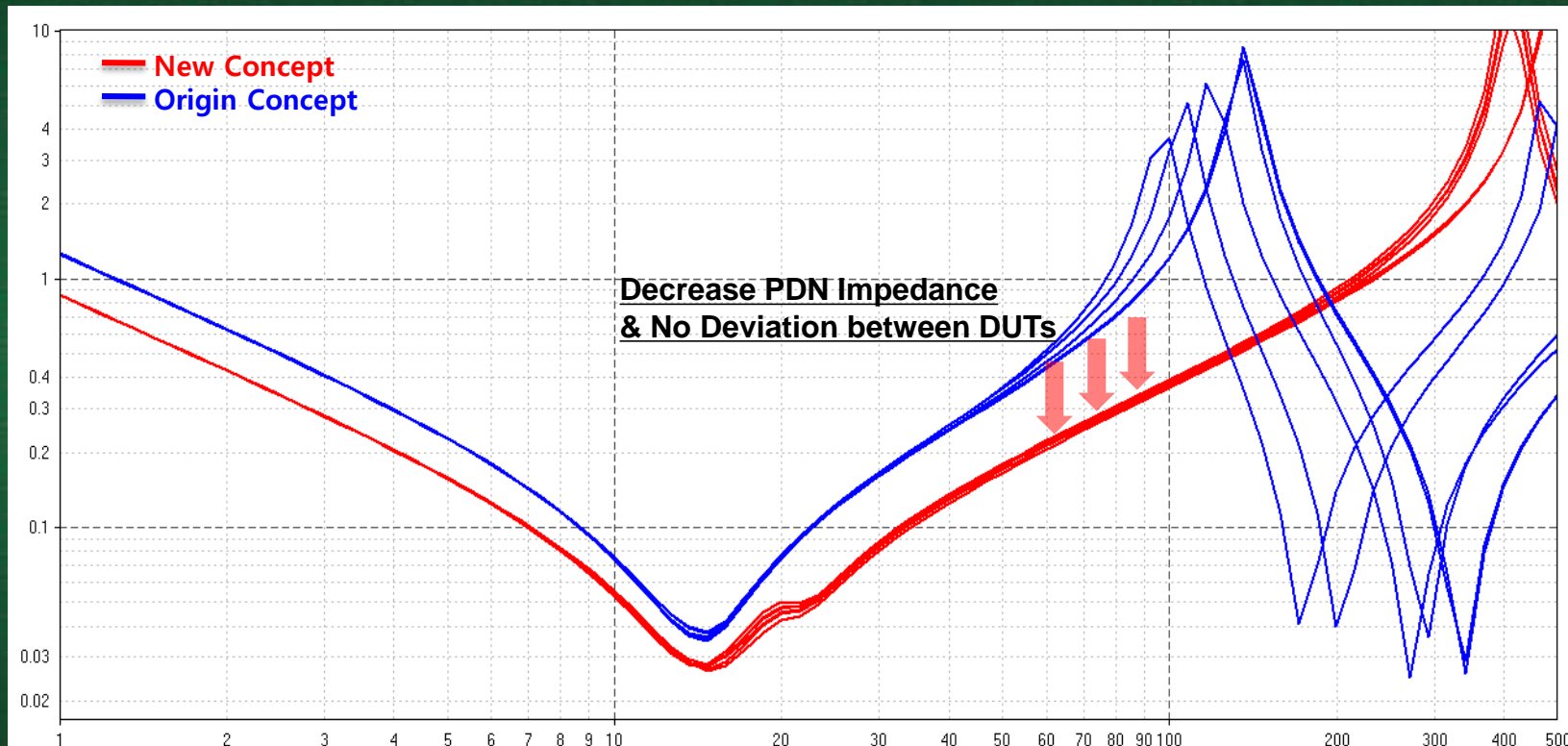
- Power DC Resistance



- Deviation between DUTs of less than $\pm 2\%$ in New Concept
- DUT - LGA Path is shortened, DC resistance reduced by more than 50%

Improve Power Integrity

- PDN Impedance

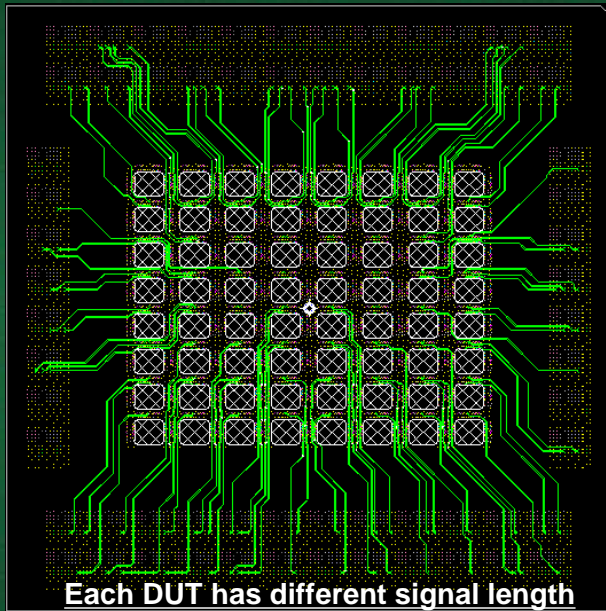


Improved PDN Impedance & Deviation between DUTs.

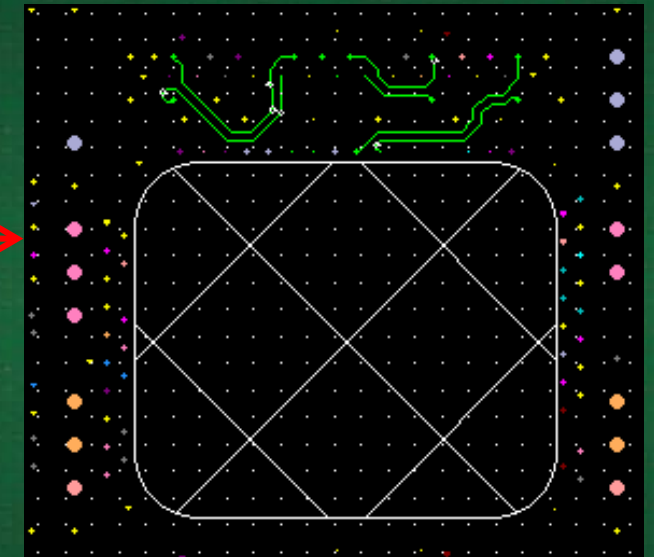
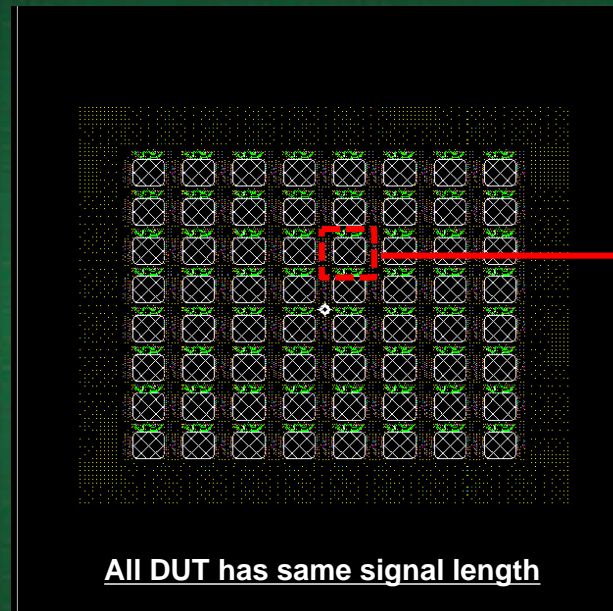
Improve Signal Integrity

- **MLC Signal Design**

[Origin Concept]



[New Concept]



	Origin Design	New Design
Signal Length (mm)	25 mm ~ 65 mm	5mm Under

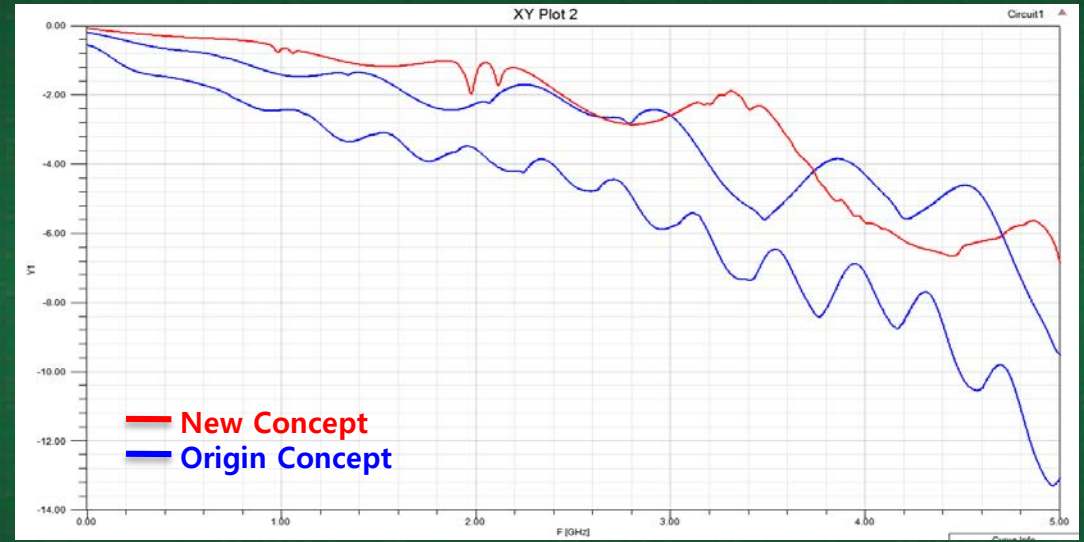
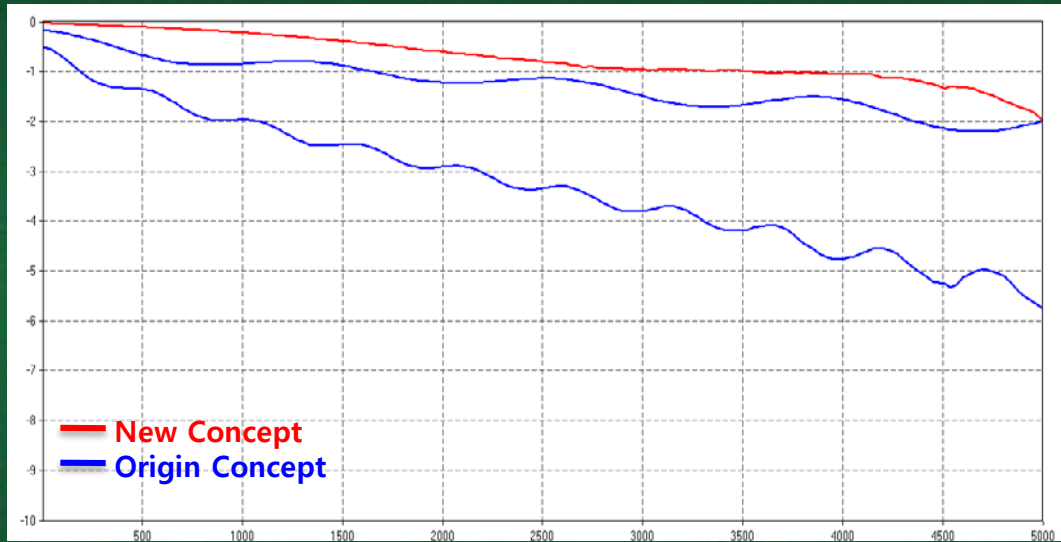
Improved SI performance due to shortened MLC trace length

Improve Signal Integrity

- Signal Integrity (Insertion Loss)

[Insertion Loss _ MLC Only]

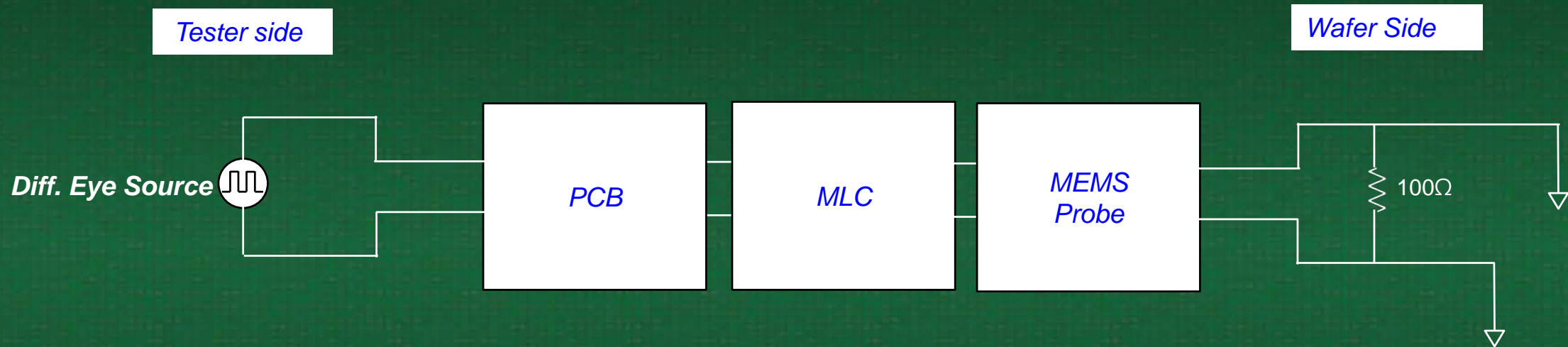
[Insertion Loss _ Full Path]



검토 항목	Insertion Loss (S21) @ 1.2GHz	
	Origin Design	New Design
MLC Only	-0.8 dB ~ -2.4 dB	<u>-0.3 dB</u>
Full Path	-1.9 ~ -3.1 dB	<u>-1.0 dB</u>

Improve Signal Integrity

- Differential Eye Simulation Condition



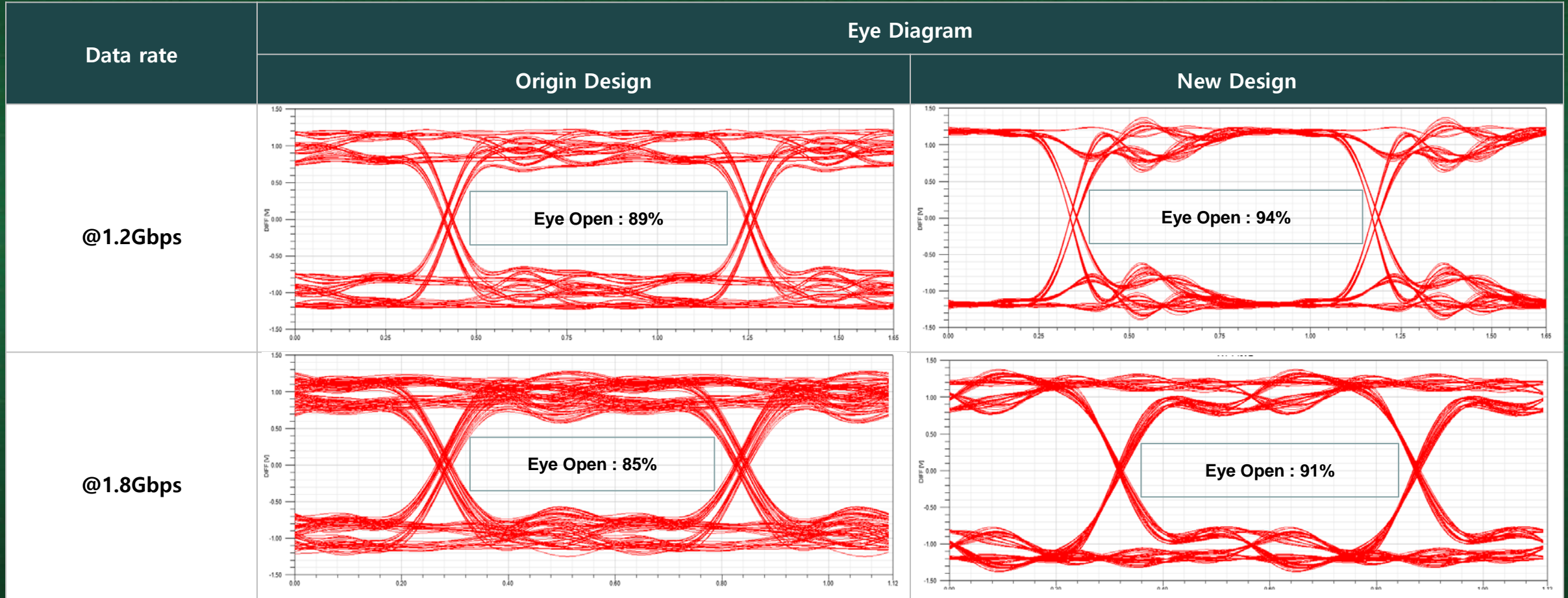
- Simulation Setup

- Input Voltage : 1.2 V
- Data rate : 1.2 / 1.8 / 2.4 / 3.2 Gbps
- Rise / Fall Time : UI/4

- Differential Impedance : 100 ohm
- Data pattern : PRBS 2⁵

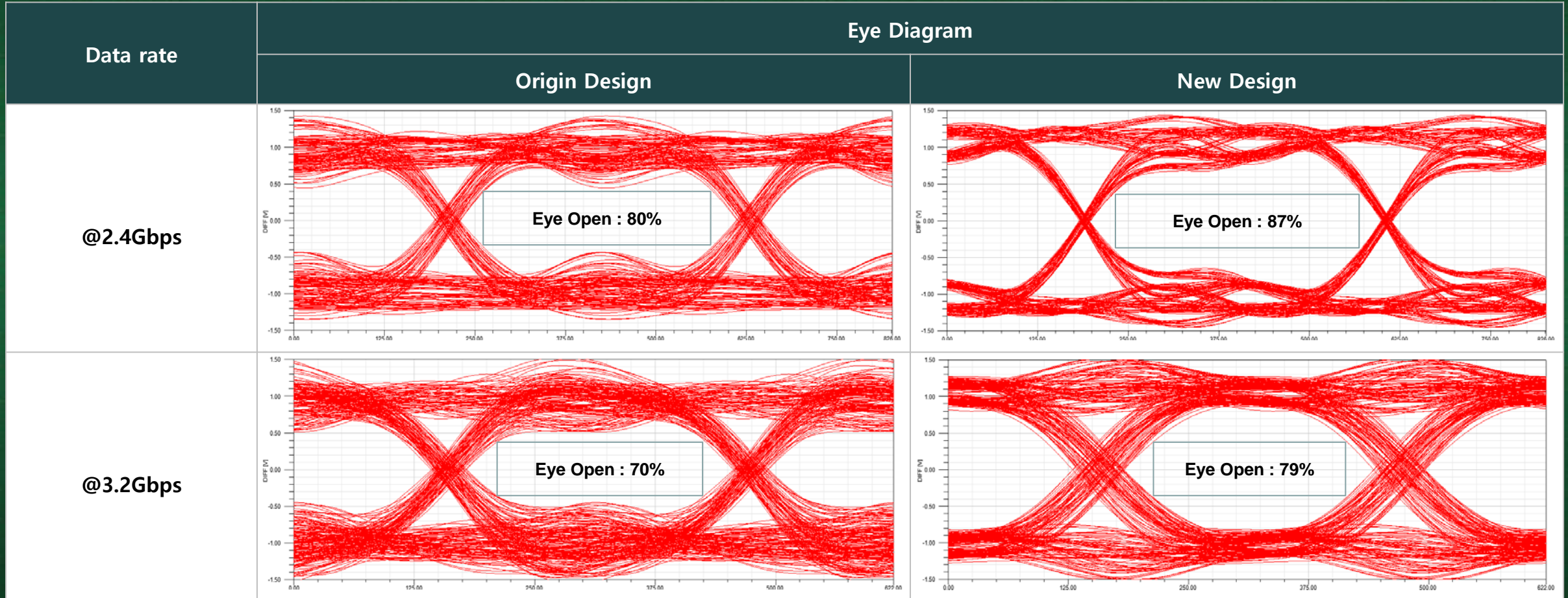
Improve Signal Integrity

- Eye Diagram @ 1.2Gbps & 1.8Gbps



Improve Signal Integrity

- Eye Diagram @ 2.4Gbps & 3.2Gbps



Conclusion

- **Currently, there is a need for high performance and para expansion in the CIS probe card test .**
- **Para extension causes PI / SI degradation and deviation between DUTs**
- **We proposed a solution to solve this problem by placing LGA in the DUT Area**
- **Overall DUTs high current Power and high speed Signal designed uniformly**
- **Improvement of PI / SI**
 - **Improvement of PI and SI has been achieved through the new structure that has short DUT – LGA path length**
- **Reduce Deviation between inner and outer DUT**
 - **Overall design uniformity → Reduced the deviation between inner and outer DUT**
- **Further research required to solve mechanical problem**
- **Thanks.**

Acknowledgements

Jung Keun Park.

Director

Willtechnology Co., Ltd.

(82-31) 240-5699

E: jkpark@willtechnology.co.kr

Hyun Min Kim

Assistant manager

Willtechnology Co., Ltd.

(82-31) 240-5670

E: hm.kim@willtechnology.co.kr

Chang Hoon Hyun

Director

Samsung Electronics Co., Ltd.

(82-10) 8881-1307

E: himan.hyun@samsung.com

Seon Ja Kim

manager

Willtechnology Co., Ltd.

(82-31) 240-5715

E: sj.kim@willtechnology.co.kr

Se Ho Lee

Staff

Willtechnology Co., Ltd.

(82-31) 240-5581

E: sh.lee@willtechnology.co.kr

Han Sung Kim

Director

Imtech Co., Ltd.

(82-31) 8071-2581

E: parksm@im-tech.co.kr

